IN THE CLAIMS

- 1 1. (Currently amended) A substrate imaging system, comprising:
- 2 a carrier holding a substrate;
- 3 a platen holding a polishing pad;
- 4 a frame for disposing the platen relative to the carrier; and
- 5 an reflectance image processing subsystem for acquiring one or more two-
- 6 dimensional images of the substrate during CMP of the substrate and deriving therefrom
- 7 from the images information about the substrate useful for subsequent CMP of the
- 8 substrate, wherein the images comprise an optical representation of at least a portion of
- 9 the substrate.
- 1 2. (Previously presented) The system of claim 1 further comprising a
- 2 rotational device for rotating the platen.
- 1 3. (Previously presented) The system of claim 1 wherein the reflectance
- 2 image processing subsystem further comprises a capturing device for capturing a
- 3 plurality of one-dimensional reflectance images and deriving the one or more two-
- 4 dimensional images therefrom.
- 4. (Original) The system of claim 1 wherein the substrate further comprises a
- 2 pad-contacting surface,
- 1 5. (Previously presented) The system of claim 4 wherein the reflectance
- 2 image processing subsystem further comprises a capturing device for capturing a
- 3 plurality of one-dimensional images from light reflected from the pad-contacting surface.
- 4 and deriving the one or more two-dimensional images therefrom.
- 1 6. (Original) The system of claim 1 wherein the one or more two-dimensional
- 2 images comprise spectral images.

- 1 7. (Original) The system of claim 1 wherein the one or more two-dimensional
- 2 images are derived from data points.
- 1 8. (Original) The system of claim 7 wherein the data points are substantially
- 2 contiguous.
- 1 9. (Original) The system of claim 7 wherein the data points are substantially
- 2 non-contiguous.
- 1 10. (Currently amended) A substrate imaging system comprising:
- a carrier holding a substrate, the substrate having a pad-contacting surface;
- 3 a platen holding a polishing pad;
- a frame for operatively disposing the platen relative to the carrier; and
- 5 an image processing subsystem for capturing, from light reflected from the pad-
- 6 contacting surface and transmitted through one or more optically transparent elements in
- 7 the platen and/or polishing pad, a plurality of one-dimensional images representative of at
- 8 least a portion of the pad-contacting surface of the substrate during traversal of the
- 9 opening and/or optically transparent elements, and deriving therefrom from the images a
- 10 frame comprising frame data providing information about the substrate useful for
- subsequent chemical-mechanical processing of the substrate, wherein the images
- 12 comprise an optical representation of at least a portion of the substrate.
- 1 11. (Previously presented) The system of claim 10 further comprising a
- 2 rotational device for rotating the platen.
- 1 12. (Original) The system of claim 10 wherein the one-dimensional images
- 2 comprise line images.
- 1 13. (Original) The system of claim 10 wherein the image processing subsystem
- 2 comprises a light source, a first bundle of optical fibers carrying light from the light
- 3 source to the slit in the platen, and a second bundle of optical fibers carrying light

- 4 reflected from the pad-contacting surface to a wavelength dispersive element for
- 5 dissecting spatial components of the one-dimensional images into their respective
- 6 wavelength components.
- 1 14. (Original) The system of claim 13 wherein the image processing subsystem
- 2 further comprises a two-dimensional imager having a spatial dimension and a spectral
- 3 dimension for receiving the dissected light from the wavelength dispersive element, and
- 4 providing a two-dimensional collection of data for each of the one-dimensional images, a
- 5 first dimension of the collection comprising a spatial dimension, and a second dimension
- 6 of the collection comprising a spectral dimension, and a processor for deriving a frame
- 7 from a plurality of the two-dimensional collections.
- 1 15. (Original) The system of claim 13 wherein the optical fibers in the first and
- 2 second bundles each have terminating ends arranged in a fiber assembly element fitted to
- 3 an underside of the platen.
- 1 16. (Original) The system of claim 15 wherein the terminating ends of the fibers
- 2 are arranged in an arrangement in which terminating ends of fibers in the first bundle
- 3 form first and second rows, and the terminating ends of fibers in the second bundle form
- 4 a third row placed between the first and second rows.
- 1 17. (Currently amended) A whole-substrate imaging system comprising:
- a carrier holding a substrate, the substrate having a pad-contacting surface with a
- 3 maximum planar dimension;
- 4 a platen having a radius and holding a polishing pad, the platen including a slit
- 5 having a length equal to or exceeding the maximum planar dimension of the substrate,
- 6 the length disposed substantially along the platen radius, and the polishing pad having an
- 7 optically transparent element located at about the slit;
- 8 a frame for operatively disposing the platen relative to the carrier, such that the
- 9 pad-contacting surface of the substrate contacts the polishing pad, and substantially

- 10 completely traverses the slit when the pad-contacting surface moves relative to the platen;
- 11 and
- an image processing subsystem for capturing, from light reflected from the pad-
- 13 contacting surface and transmitted through the optically transparent element and the slit,
- 14 a plurality of one-dimensional images representative of the substantial entirety of the pad-
- 15 contacting surface of the substrate during traversal of the pad-contacting surface past the
- 16 slit, and deriving therefrom from the images a frame comprising frame data useful for
- 17 subsequent chemical-mechanical processing of the substrate, wherein the images
- 18 comprise an optical representation of one or more portions of the substrate.
- 1 18. (Previously presented) The system of claim 17 further comprising a
- 2 rotational device for rotating the platen.
- 1 19. (Original) The system of claim 17 wherein the one-dimensional images
- 2 comprise line images.
- 1 20. (Original) The system of claim 17 wherein the image processing subsystem
- 2 comprises a light source, a first bundle of optical fibers carrying light from the light
- 3 source to the slit in the platen, and a second bundle of optical fibers carrying light
- 4 reflected from the pad-contacting surface to a wavelength dispersive element for
- 5 dissecting spatial components of the one-dimensional images into their respective
- 6 wavelength components.
- 1 21. (Original) The system of claim 20 wherein the image processing subsystem
- 2 further comprises a two-dimensional imager having a spatial dimension and a spectral
- 3 dimension for receiving dissected light from the wavelength dispersive element, and
- 4 providing a two-dimensional collection of data for each of the one-dimensional images, a
- 5 first dimension of the collection comprising a spatial dimension, and a second dimension
- 6 of the collection comprising a spectral dimension, and a processor for deriving a frame
- 7 from a plurality of two-dimensional collections.

- 1 22. (Original) The system of claim 20 wherein the optical fibers in the first and
- 2 second bundles each have terminating ends arranged in a fiber assembly element fitted to
- 3 an underside of the platen.
- 1 23. (Original) The system of claim 22 wherein the terminating ends of the fibers
- 2 are arranged in an arrangement in which terminating ends of fibers in the first bundle
- 3 form first and second rows, and the terminating ends of fibers in the second bundle form
- 4 a third row placed between the first and second rows.
- 1 24. (Withdrawn) A whole-die imaging system comprising:
- a carrier holding a substrate, the substrate having a pad-contacting surface
- 3 forming a die and having a maximum planar dimension;
- 4 a rotating platen having a radius and holding a polishing pad, the platen including
- 5 a slit having a length approximately equal to the maximum planar dimension of the die,
- 6 the length disposed substantially along the platen radius, and the polishing pad having an
- 7 optically transparent element located at about the slit;
- 8 a frame for operatively disposing the rotating platen relative to the carrier, such
- 9 that the pad-contacting surface of the substrate contacts the polishing pad, and
- 10 substantially completely traverses the slit within a rotation of the platen; and
- an image processing subsystem for capturing, from light reflected from the pad-
- 12 contacting surface and transmitted through the optically transparent element and the slit,
- 13 a plurality of one-dimensional images representative of the substantial entirety of the pad-
- 14 contacting surface of the die during traversal of the pad-contacting surface past the slit,
- 15 and deriving therefrom a frame comprising frame data providing information about the
- 16 die useful for subsequent chemical-mechanical processing of the substrate.
- 1 25. (Withdrawn) The system of claim 24 wherein the one-dimensional images
- 2 comprise line images.
- 1 26. (Withdrawn) The system of claim 24 wherein the image processing subsystem
- 2 comprises a light source, a first bundle of optical fibers carrying light from the light

- 3 source to the slit in the platen, and a second bundle of optical fibers carrying light
- 4 reflected from the pad-contacting surface to a wavelength dispersive element for
- 5 dissecting spatial components of the one-dimensional images into their respective
- 6 wavelength components.
- 1 27. (Withdrawn) The system of claim 26 wherein the image processing subsystem
- 2 further comprises a two-dimensional imager having a spatial dimension and a spectral
- 3 dimension for receiving dissected light from the wavelength dispersive element, and
- 4 providing a two-dimensional collection of data for each of the one-dimensional images, a
- 5 first dimension of the collection comprising a spatial dimension, and a second dimension
- 6 of the collection comprising a spectral dimension, and a processor for deriving a frame
- 7 from a plurality of two-dimensional collections.
- 1 28. (Withdrawn) The system of claim 26 wherein the optical fibers in the first and
- 2 second bundles each have terminating ends arranged in a fiber assembly element fitted to
- 3 an underside of the platen.
- 1 29. (Withdrawn) The system of claim 28 wherein the terminating ends of the fibers
- 2 are arranged in an arrangement in which terminating ends of fibers in the first bundle
- 3 form first and second rows, and the terminating ends of fibers in the second bundle form
- 4 a third row placed between the first and second rows.
- 1 30. (Currently amended) A system for imaging a substrate during CMP, comprising:
- 2 a carrier holding a substrate, the substrate having a pad-contacting surface;
- 3 a rotating platen holding a polishing pad;
- a frame for operatively disposing the rotating platen relative to the carrier; and
- an image processing subsystem for capturing, from light reflected from the pad-
- 6 contacting surface and transmitted through one or more optically transparent elements in
- 7 the platen and/or polishing pad, data points representative of at least a portion of the pad-
- 8 contacting surface of the substrate during traversal of the opening and/or optically
- 9 transparent elements, and deriving therefrom from the data points one or more one-

- 10 dimensional reflectance images of a portion of a substrate, where data point spacing is
- determined by an array of data collection locations disposed substantially non-parallel to
- 12 the direction of substrate motion, wherein the reflectance images comprise an optical
- 13 representation of the portion of the substrate.
- 1 31. (Original) The system of claim 30 where the data points used for deriving the
- 2 one or more images are substantially contiguous.
- 1 32. (Original) The system of claim 31 where the data points used for deriving the
- 2 one or more images are substantially non-contiguous.
- 1 33. (Previously presented) The system of claim 30 where the one or more
- 2 images are spectral images.
- 1 34. (Original) The system of claim 30 where the image processing subsystem
- 2 aggregates the one-dimensional images to form a two-dimensional image of the substrate,
- 3 and the two-dimensional image provides information about the substrate useful for
- 4 subsequent chemical-mechanical processing of the substrate.
- 1 35. (Original) The system of claim 34 where the image processing subsystem
- 2 forms one or more two-dimensional images of at least a portion of the substrate.
- 1 36. (Original) The system of claim 35 where the data points used for deriving the
- 2 one or more images are substantially contiguous.
- 1 37. (Original) The system of claim 35 where the points used for deriving the one
- 2 or more images are substantially non-contiguous.
- 1 38. (Previously presented) The system of claim 35 where the one or more two-
- 2 dimensional images comprise spectral images.

- 1 39. (Currently amended) A method for polishing a semiconductor substrate,
- 2 comprising:
- 3 acquiring one or more two-dimensional images of the substrate during CMP.
- 4 wherein the images comprise an optical representation of at least a portion of the
- 5 substrate; and
- 6 deriving therefrom from the images information about the substrate useful for
- 7 subsequent chemical-mechanical processing of the substrate.
- 1 40. (Original) The method of claim 39 wherein the derived information
- 2 comprises frame data suitable for reproducing the one or more two-dimensional images.
- 1 41. (Original) The method of claim 39 wherein each two dimensional image
- 2 comprises a plurality of one-dimensional images, each one-dimensional image reflected
- 3 from a different portion of the substrate.
- 1 42. (Original) The method of claim 39 wherein the one or more two-dimensional
- 2 images comprise spectral images.
- 1 43. (Currently amended) A method of imaging a substrate comprising:
- 2 holding a substrate having a pad-contacting surface;
- 3 holding a polishing pad with a rotating platen including one or more optically
- 4 transparent elements;
- 5 operatively disposing the rotating platen relative to the pad-contacting surface,
- 6 such that the pad-contacting surface contacts the polishing pad, and substantially
- 7 completely traverses the one or more optically transparent elements within a rotation of
- 8 the rotating platen;
- 9 capturing, from light reflected from the pad-contacting surface and transmitted
- 10 through the one or more optically transparent elements, a plurality of one-dimensional
- images representative of at least a portion of the pad-contacting surface during traversal
- 12 of the pad-contacting surface past the optically transparent elements, wherein the images
- 13 comprise an optical representation of at least a portion of the substrate; and

- deriving therefrom from the images a frame comprising frame data useful for subsequent chemical-mechanical processing of the substrate.
- 1 Claim 44 (canceled).
- 1 45. (Previously presented) The method of claim 43 wherein the capturing
- 2 comprises:
- 3 carrying light from a light source to the optically transparent elements in the
- 4 platen;
- 5 carrying light reflected from the pad-contacting surface to a wavelength
- 6 dispersive element; and
- 7 dissecting spatial components of the one-dimensional images into their respective
- 8 wavelength components.
- 1 46. (Currently amended) The method of claim 44 45 wherein the capturing further
- 2 comprises:
- 3 receiving, at a two-dimensional imager having a spatial dimension and a spectral
- 4 dimension, dissected light from the wavelength dispersive element; and
- 5 providing a two-dimensional collection of data for each of the one-dimensional
- 6 images, a first dimension of the collection comprising a spatial dimension, and a second
- 7 dimension of the collection comprising a spectral dimension.
- 1 47. (Previously presented) The method of claim 46 wherein the deriving
- 2 comprises deriving a frame from a plurality of the two-dimensional collections.
- 1 48. (Currently amended) A method for acquiring a two-dimensional image of a
- 2 substrate during CMP, comprising:
- 3 holding a substrate, the substrate having a pad-contacting surface and a maximum
- 4 planar dimension;
- 5 holding a polishing pad with a rotating platen, the platen having a radius and
- 6 including a slit having a length disposed substantially along the radius of the platen and

7	equal to or exceeding the maximum planar dimension of the substrate, the platen also
8	including an optically transparent element located at about the slit;
9	operatively disposing the rotating platen relative to the pad-contacting surface,
10	such that the pad-contacting surface of the substrate contacts the polishing pad, and
11	substantially completely traverses the slit within a rotation of the platen;
12	capturing, from light reflected from the pad-contacting surface and transmitted
13	through the optically transparent element, a plurality of one-dimensional images
14	representative of the substantial entirety of the pad-contacting surface of the substrate
15	during traversal of the pad-contacting surface past the slit, wherein the images comprise
16	an optical representation of at least a portion of the substrate; and
17	deriving therefrom from the images a frame comprising frame data providing
18	information about the substrate useful for subsequent chemical-mechanical processing of
19	the substrate.
1	49. (Previously presented) The method of claim 48 wherein the capturing
2	comprises:
3	carrying light from a light source to the slit in the platen;
4	carrying light reflected from the pad-contacting surface to a wavelength
5	dispersive element; and
6	dissecting spatial components of the one-dimensional images into their respective
7	wavelength components.

- 2 further comprises:
- 3 receiving, at a two-dimensional imager having a spatial dimension and a spectral
- 4 dimension, dissected light from the wavelength dispersive element; and
- 5 providing a two-dimensional collection of data for each of the one-dimensional
- 6 images, a first dimension of the collection comprising a spatial dimension, and a second
- 7 dimension of the collection comprising a spectral dimension.

- 1 51. (Previously presented) The method of claim 50 wherein the deriving
- 2 comprises deriving a frame from a plurality of the two-dimensional collections.